

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Beng Ghee Tan  
Serial No: TBA (371 National Filing of PCT/SG03/00022 filed February 5, 2003)  
Filed: July 20, 2005  
For: A Method for Detecting and Monitoring Wafer Probing Process Instability  
Confirmation No: TBA  
Group Art Unit: TBA  
Examiner: TBA  
HDP Ref: 5731-000014/US/NP

July 20, 2005

**PRELIMINARY AMENDMENT A**

TO THE COMMISSIONER FOR PATENTS,  
SIR/MADAM:

Prior to examination and before calculation of the filing fee for the present application, please enter the following amendments and remarks.

Amendments to the specification begin on page 2 of this paper.

The specification as it should appear following amendments begins on page 3 of this paper.

Amendments to the claims are reflected in the Listing of Claims, which begins on page 10 of this paper.

Remarks begin on page 13 of this paper.